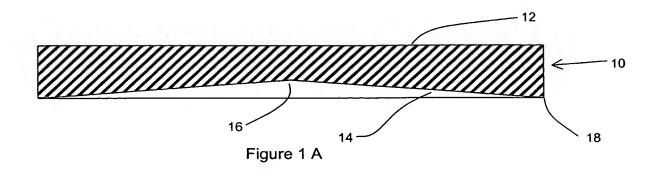
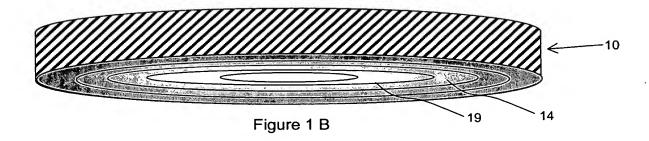
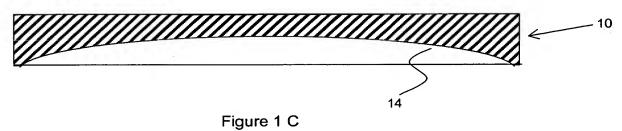
D-21,385 HIGH PURITY FERROMAGNETIC SPUTTER TARGET, ASSEMBLY AND METHOD OF MANUFACTURING SAME Koenigsmann et al. Page 1 of 2







i iguic i o

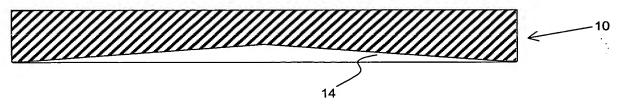


Figure 1 D

D-21,385 HIGH PURITY FERROMAGNETIC SPUTTER TARGET, ASSEMBLY AND METHOD OF MANUFACTURING SAME Koenigsmann et al. Page 2 of 2

